

Thin Film Metrology and Processing Improvements at Luxel Corporation

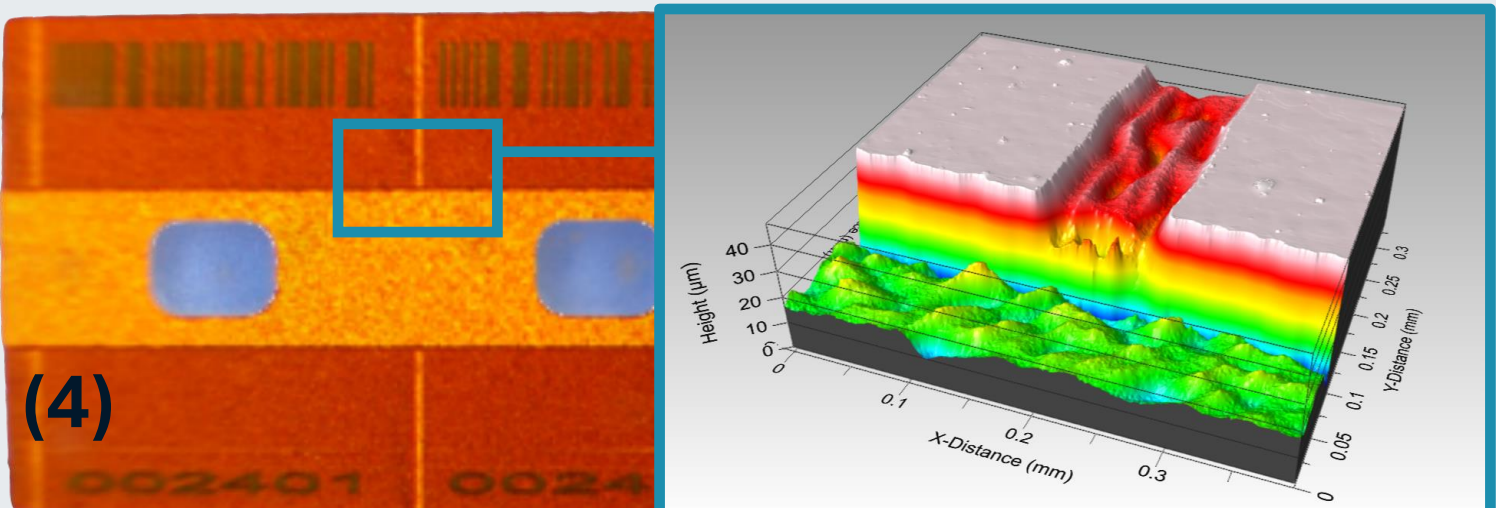
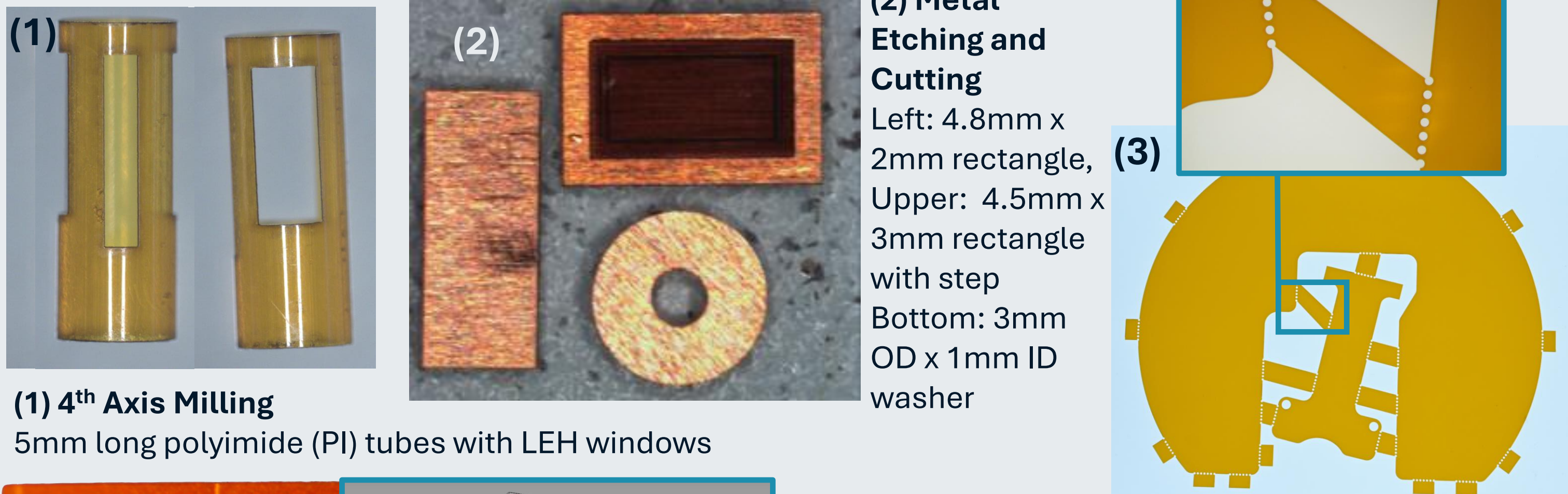
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Component Fabrication

UV Laser Machining

- 3Watt, 20µm spot size, 355nm UV-laser
- Marking area: 170mm x 170mm. Larger areas are made possible by a multi-axis stage
- Rotary axis enabling milling of curved surfaces



(4) Highly Uniform and Repeatable Etched Profiles
Luxel's GridTape® - 4mm wide x 30µm deep trough etched into the backside of the tape as well as a 10µm deep vent path every 6mm.

(3) High Precision over Large Area
170mm x 75µm thick Kapton with 750µm diameter perforations

Test Verified Materials		
Metals including:	Al, Cu, Ti, Ta, Mo, Zr, Sn, In, 304 SS	Up to 300µm
Plastics including:	CH, PET, PI	Up to 500µm

Component Inspection

Visible Light Microscope Multi-Sensor Measurement System White Light Interferometer

Qualitative inspections of freestanding films	300x300mm measurement area	Areal roughness characterization
Quality imaging	Dimensional inspection	Step height
Quick dimensional checks	Large area flatness verification	Quantitative texture and form
Defect characterization	Programmable for high throughput	Edge roll-off characterization

Target Assembly Workflow

Component Fabrication

Milling, Turning, Drilling

UV Laser Machining

Fabrication of Ultrathin Freestanding Films

Polyimides: 50nm – 5µm

Metal Coatings: 3nm – 5µm

Component Inspection

Visible Light Microscope

Multi-Sensor Measurement System

White Light Interferometer

Film Thickness Verification

Stylus Profilometer

Reflectometer

Ellipsometer

Target Assembly

Pressure Testing

Low Pressure Bleed Down

Helium Leak Detection

In-situ Deflection Measurements

High Pressure Bleed Down Testing

Destructive Analysis

Auxiliary Metrology Tools

Confocal Profilometer

Visible Light Microscopes

Infrared to UV Spectrometers

White Light Interferometer

Scanning Electron Microscope

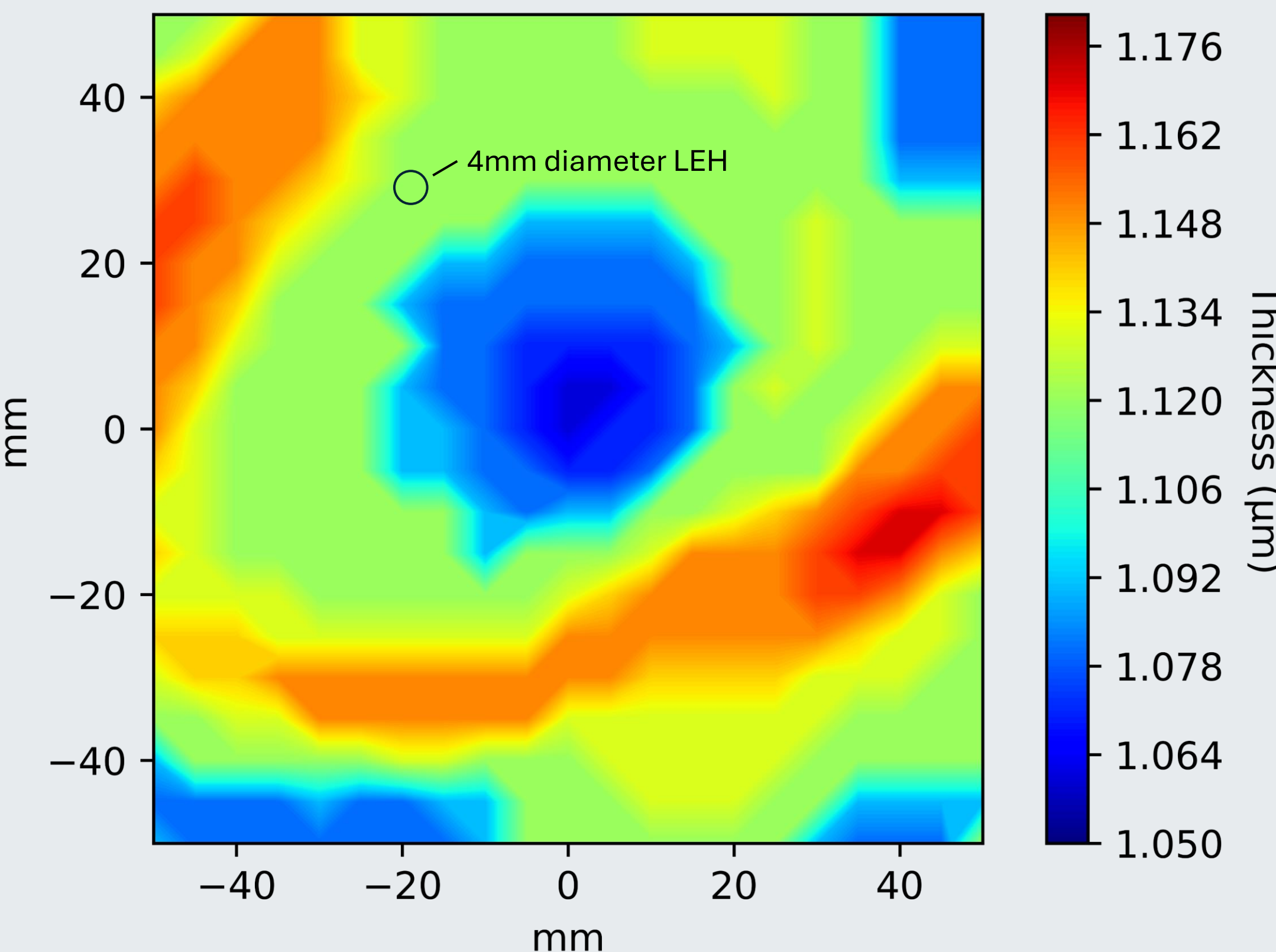
Energy Dispersive X-ray Spectrometer

Delivery of Laser Targets

Film Thickness Verification

Ellipsometer

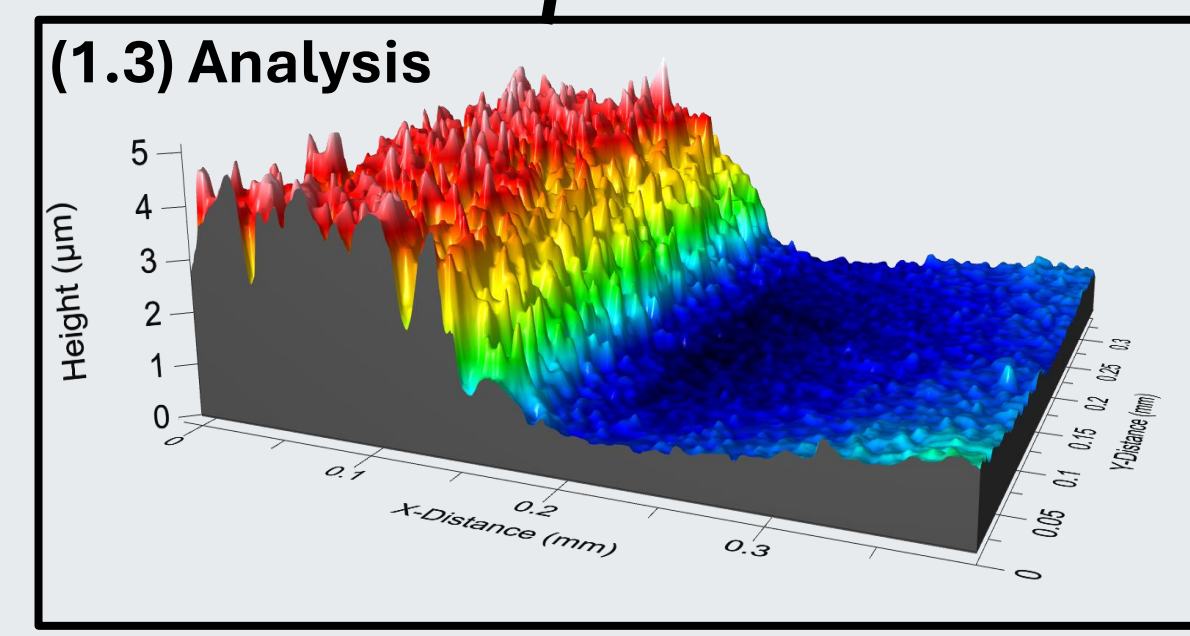
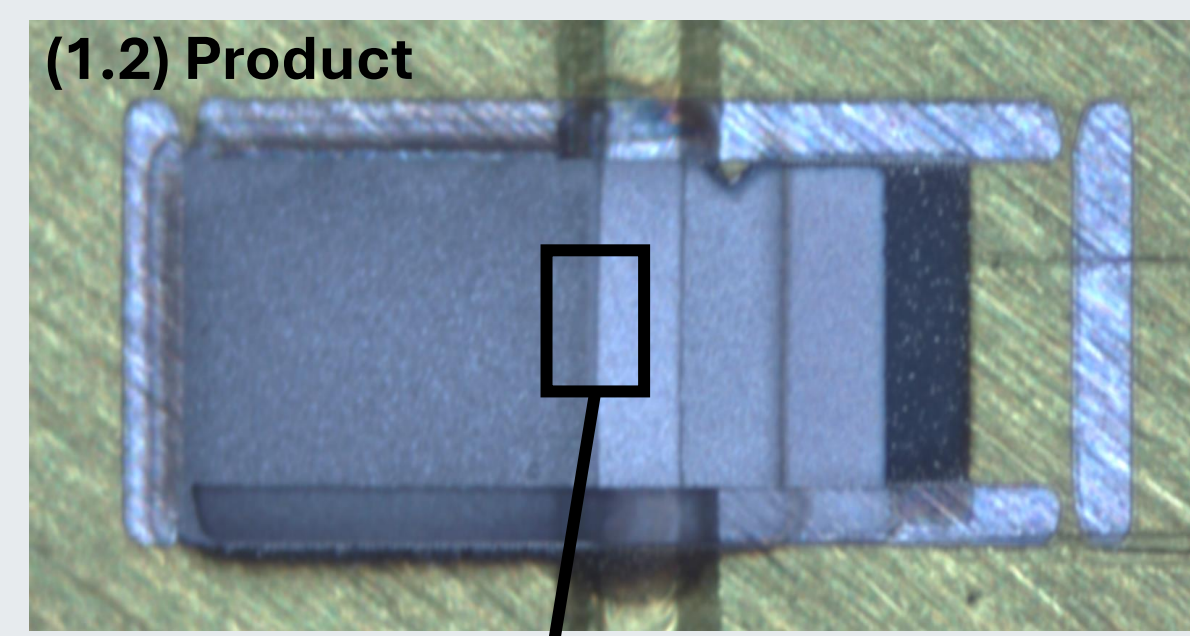
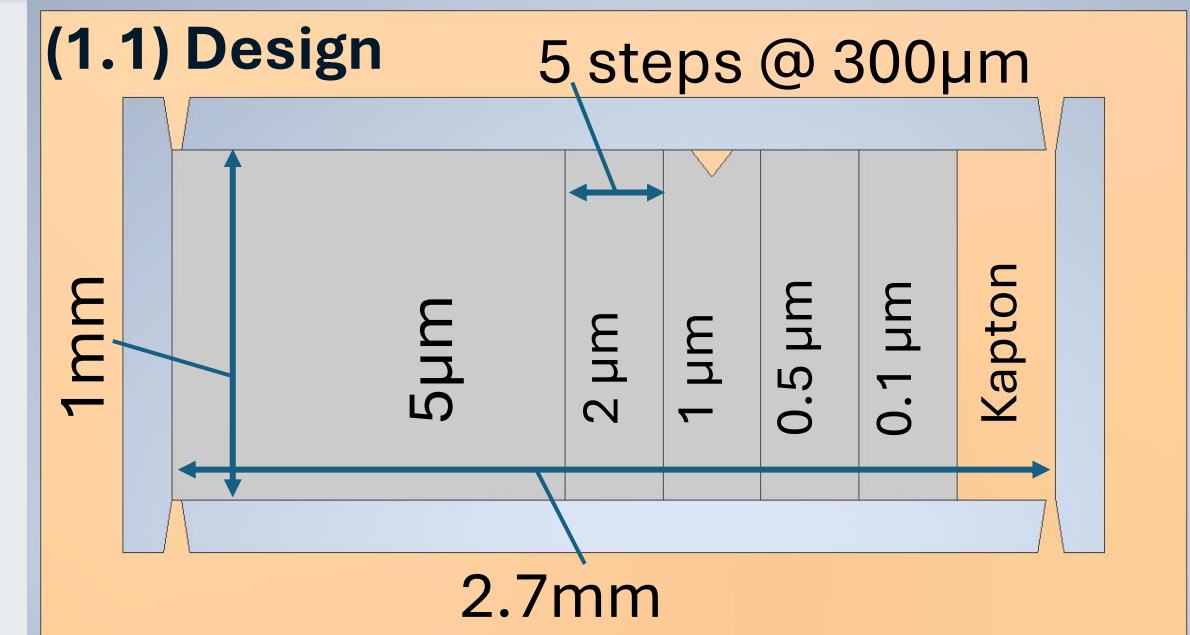
- Ellipsometry enables non-contact measurements of transparent films
- Standard material non-uniformity is ~5% across a 140mm diameter area
- Large area film mapping and precise measurement of smaller films with tighter tolerances.



Pressure Testing

Pressure System	Test Type	Volume (L)	Sensitivity (Torr*L/s)	Frame Type	Connection	Pressure Limit (atm)	Gases
Gas pipe Test System	Rate-of-fall	1.38E-03	5E-05	Gaspipe with fill tubes	PTFE tubing	5.0	Air, N ₂
NIF Test System	Rate-of-fall	8.24E-03	5E-05	Planar	O-ring	27.0	He, Air, N ₂ , Ar, Kr
				Non-Planar	Epoxy or VCR		
	Helium Leak Detection	N/A	5E-11	Planar	O-ring	2.0	He

White Light Interferometry



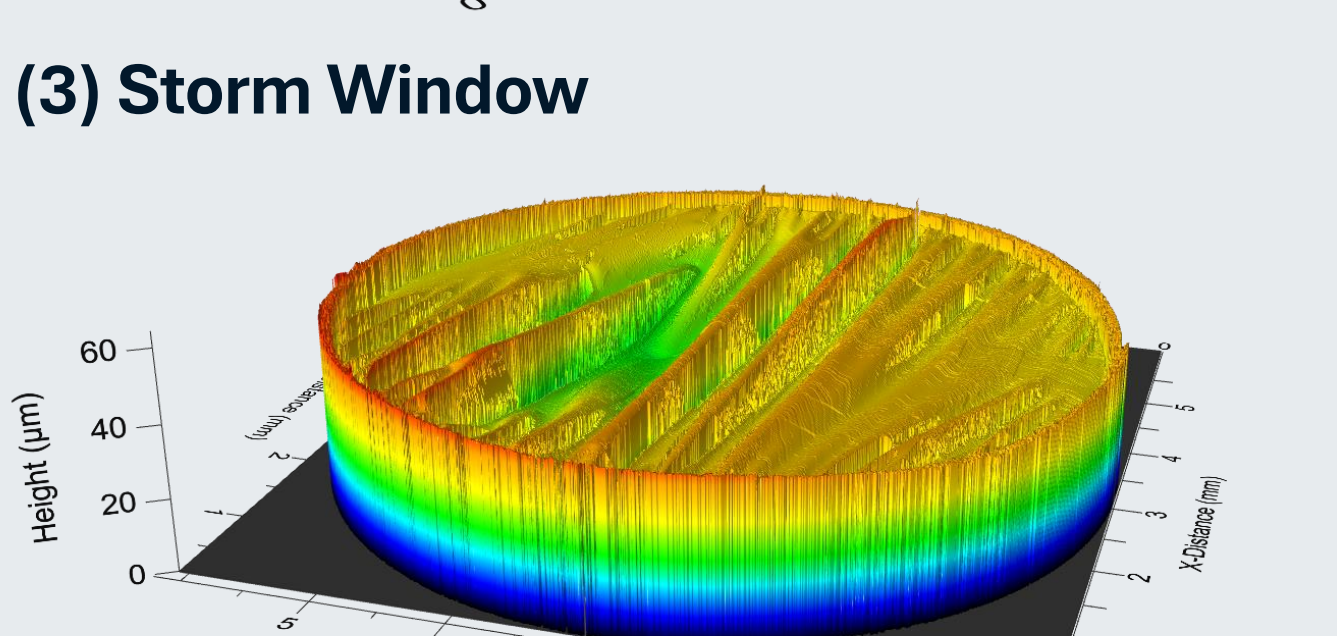
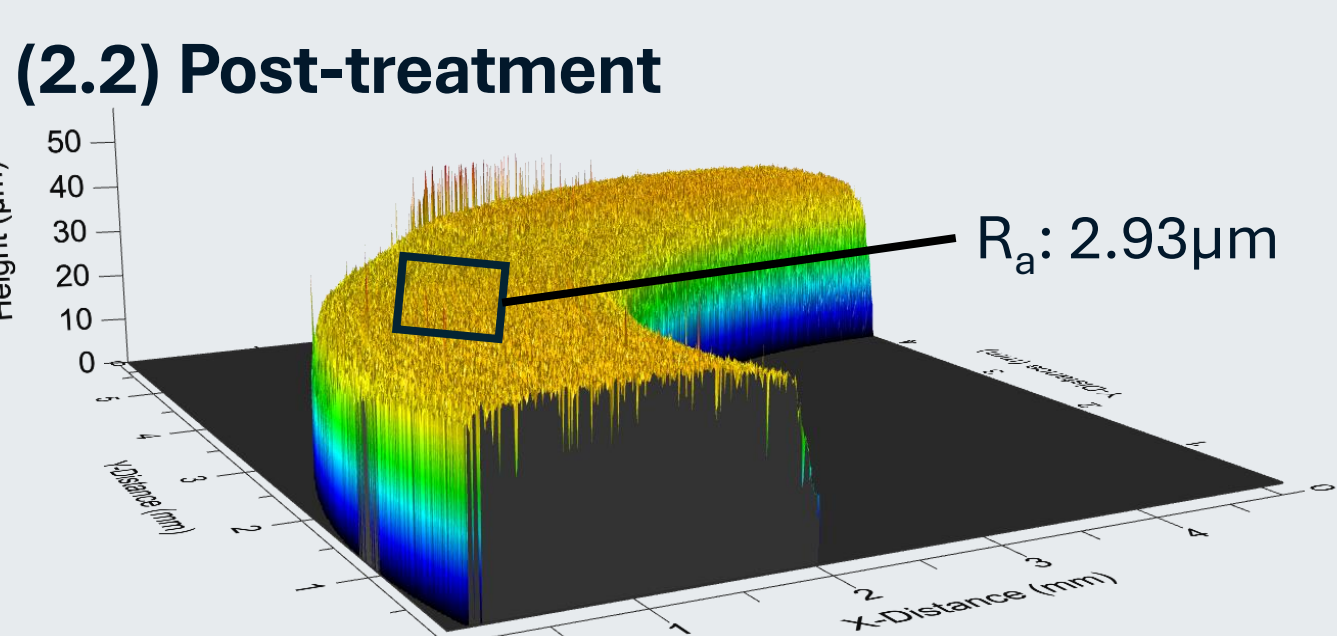
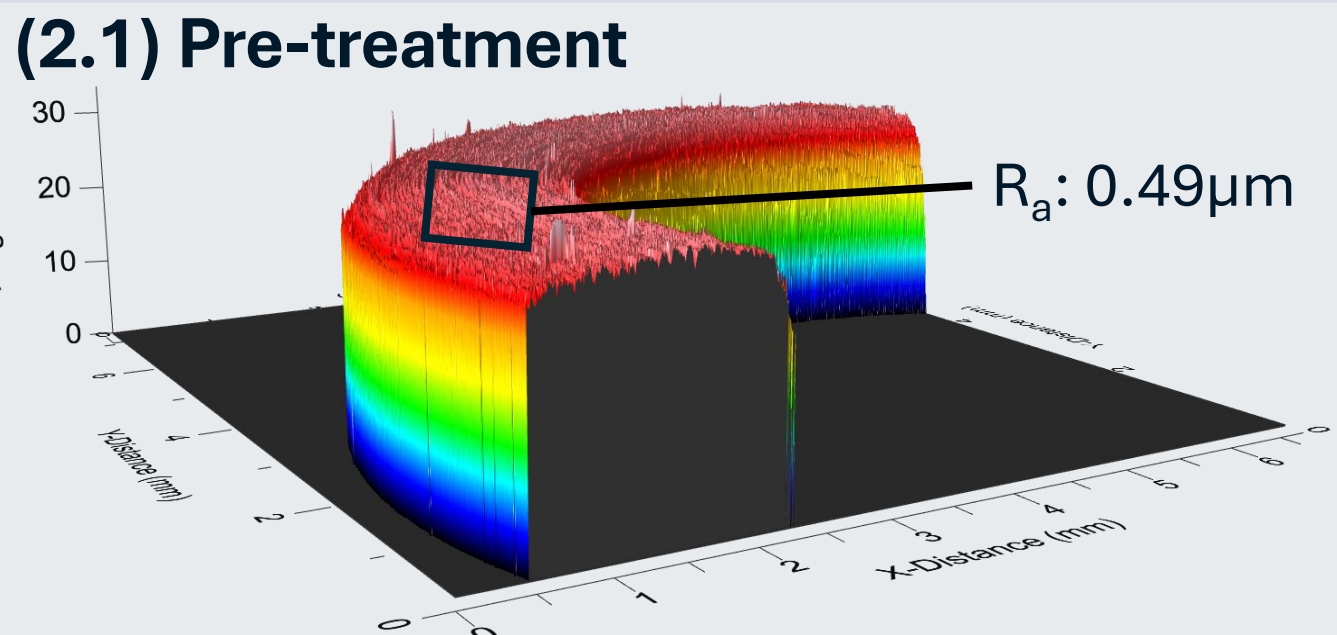
(1) PVD Coating Characterization
A multi-step Sn coating is analyzed for step height, and roll-off to meet tight spatial tolerances.

Dimension	Target	Measured
Step Height	3µm±0.3µm	3.09µm
Roll-off	<50.0µm	36.4µm

(2) 3D Roughness Analysis
LEH washer surfaces are analyzed to optimize treatment processes for maximum LEH window adhesion. 1mmx1mm Area Measurements
2.1 : Pre-treatment: 0.49µm
2.2 : Post-treatment: 2.93µm

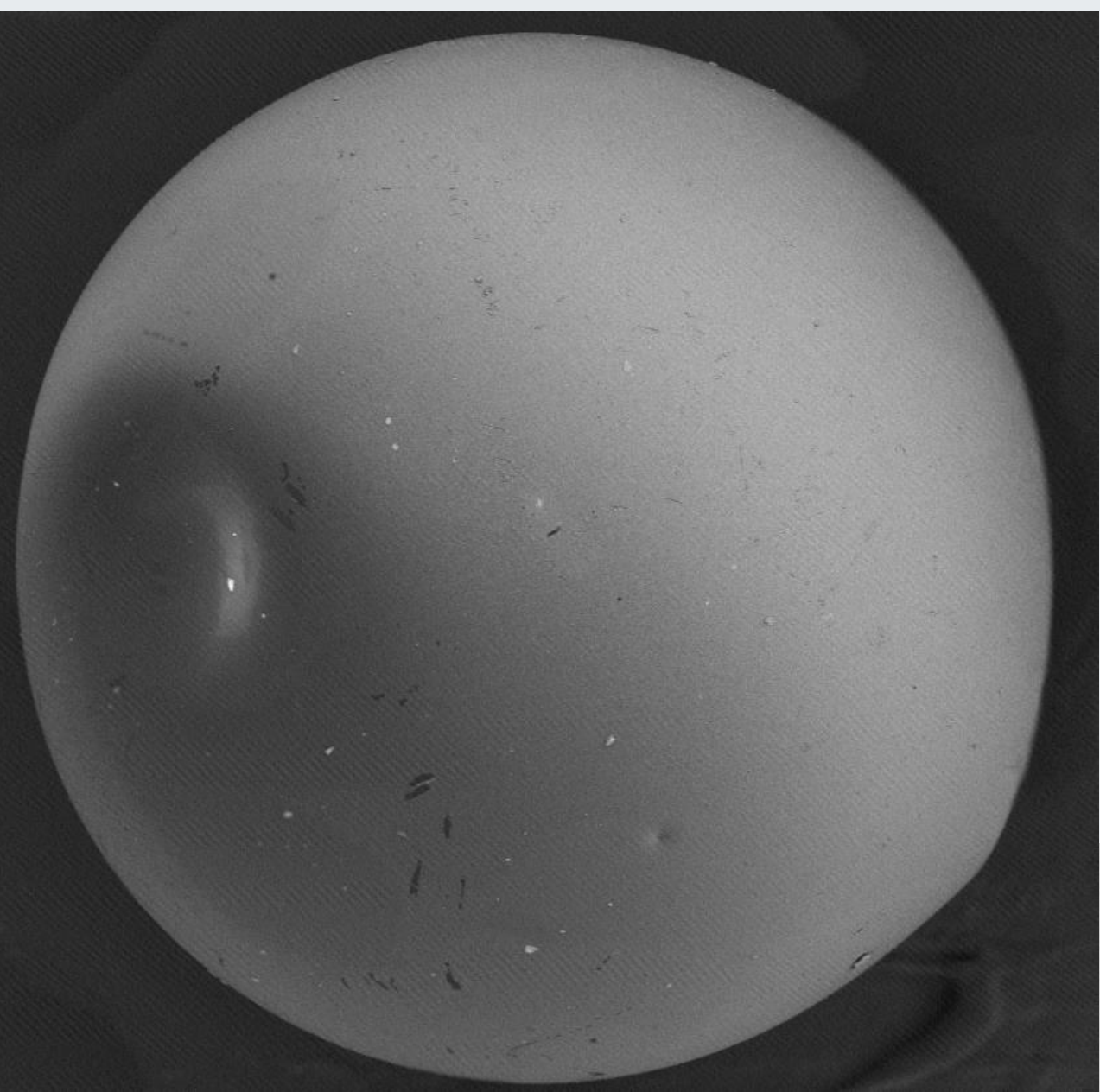
(3) Large Area Topography
Stitch-scanning allows for large area mapping and topographical maps. A storm window's waviness and ID transition is analyzed via line scan of a stitched map.

5.79mm ID x 100nm LUXFilm® Polyimide / 40nm Carbon.



Auxiliary Film Metrology

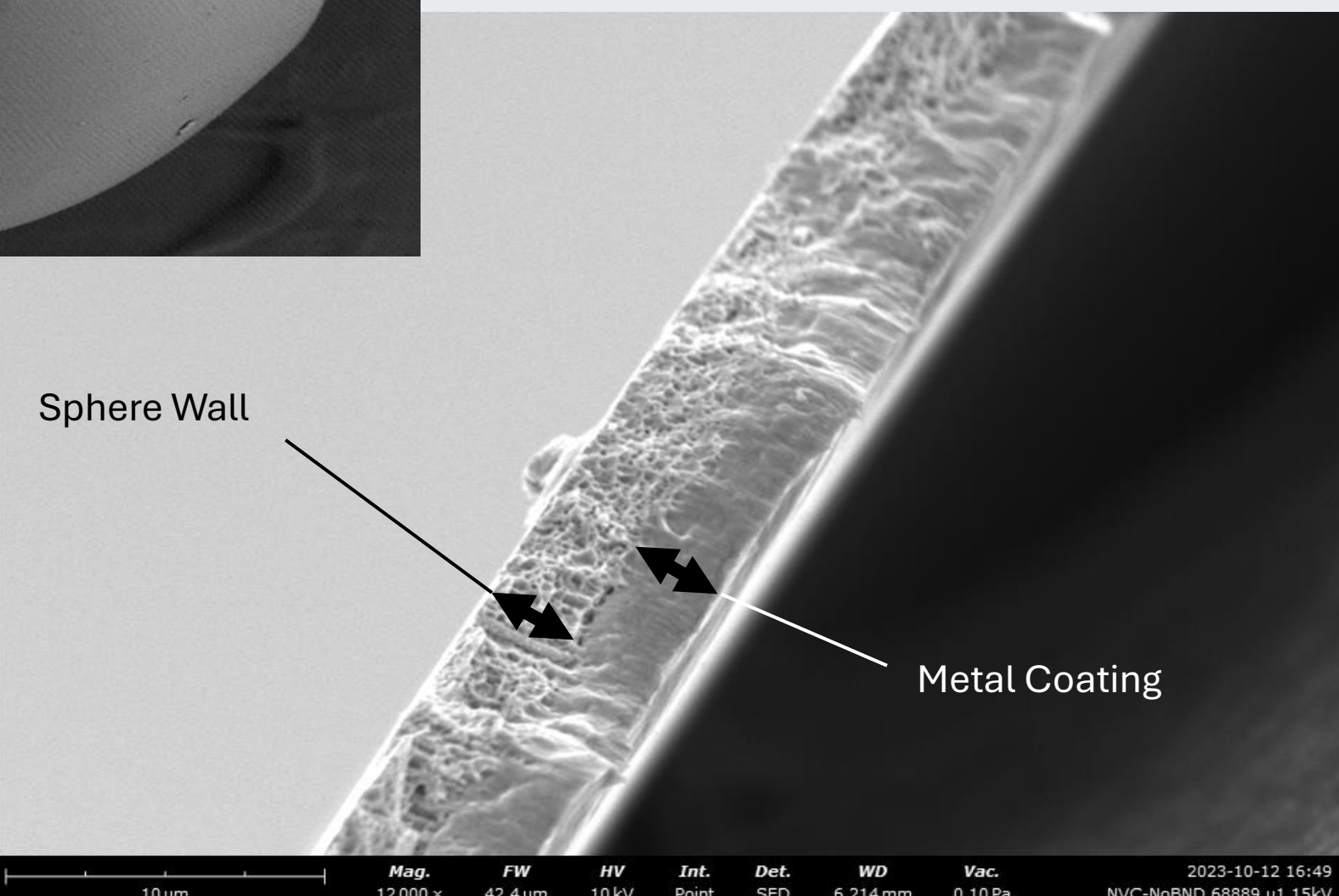
Scanning Electron Microscopy



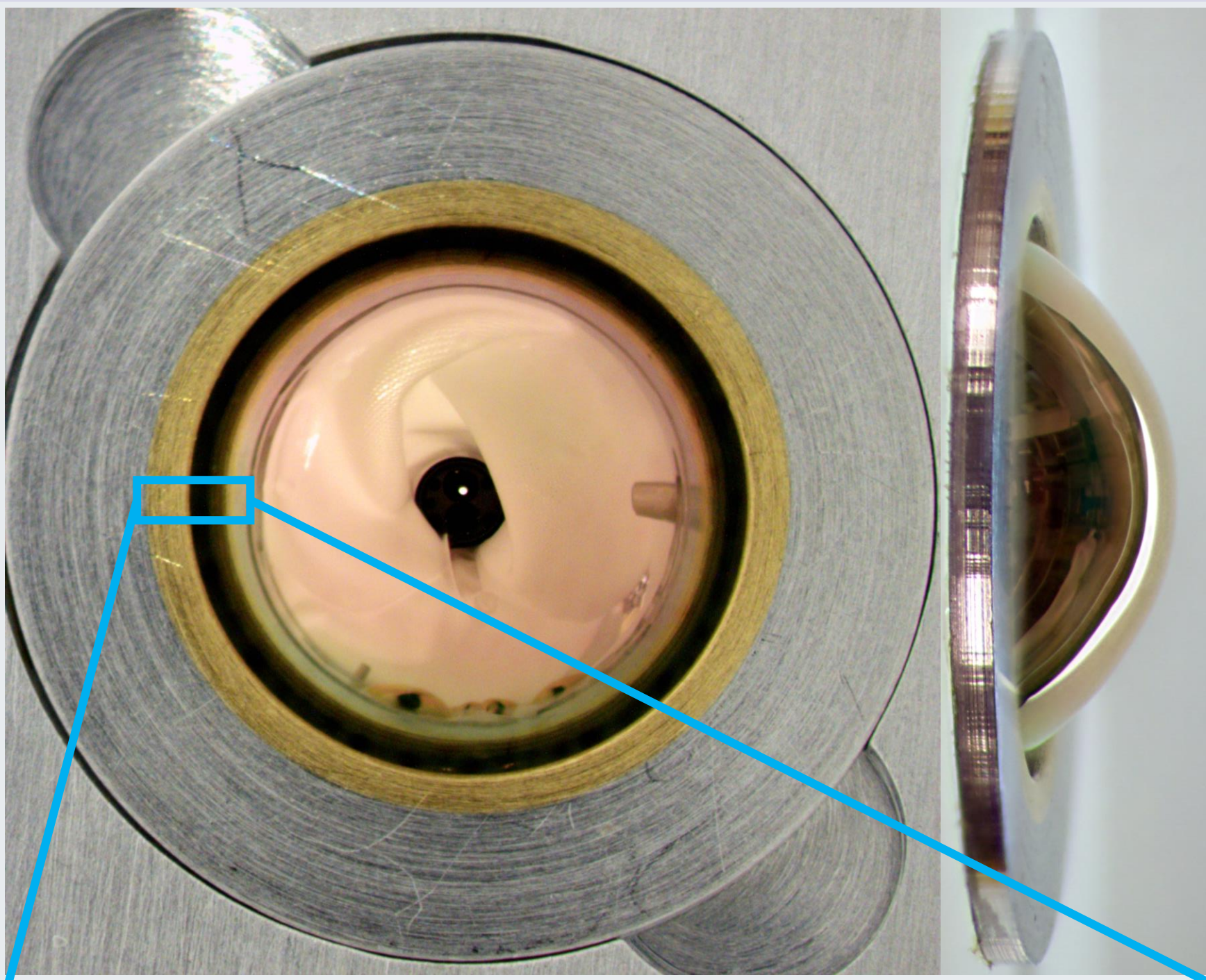
Surface Coating Characterization

Left: 0.5mm diameter metal-coated polymer sphere.

Below: Cross-section view of metal coating on polymer sphere wall. Qualitative assessment of thickness uniformity and adhesion.



Energy Dispersive X-ray Spectroscopy



Spatially Resolved Compositional Analysis

6mm ID 40nm Au-coating on 1.0µm LUXFilm® Polyimide domes.

LUXFilm® Polyimide is shaped into a near-hemispherical shape before the Au coating.

EDS analysis was conducted to evaluate the shadowing effect of the washer during deposition.

